

ASMJP.055C1



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoh et al.
Appl. No. : 10/759,925
Filed : January 16, 2004
For : SEMICONDUCTOR
PROCESSING WITH A REMOTE
PLASMA SOURCE FOR SELF-
CLEANING
Examiner : M. Kornakov
Group Art Unit : 1746

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

May 13, 2005

(Date)

Adeel S. Akhtar
Adeel S. Akhtar, Reg. No. 41,394

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed on March 15, 2005, please amend the above-captioned application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.

*Do not
enter
MK 05/24/05*